

Docket No. 060188-0658



ZFW

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of : Customer Number: 20277
Masashi HAMANAKA, et al. : Confirmation Number: 8488
Application No.: 10/671,502 : Group Art Unit: 3723
Filed: September 29, 2003 : Examiner: RACHUBA, MAURINA T

For: POLISHING METHOD FOR SEMICONDUCTOR DEVICE, METHOD FOR
FABRICATING SEMICONDUCTOR DEVICE AND POLISHING SYSTEM

INFORMATION DISCLOSURE STATEMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed more than three months after the U.S. filing date AND after the mailing date of the first Office Action on the merits, but before the mailing date of a Final Rejection or Notice of Allowance.

CERTIFICATION PARAGRAPH

The undersigned certifies that each item of information contained in this Information Disclosure Statement was first cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this Information Disclosure Statement as described in 37 CFR 1.97(e)(1).

Each non-English language reference was cited in a corresponding foreign application office action and its relevance discussed therein. A copy of the foreign office action, together with an English language version thereof, is attached for the Examiner's information.

Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account 500417 and please credit any excess fees to such deposit account.

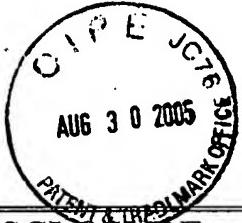
Respectfully submitted,

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SHEET 1 OF 1

INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449)				ATTY. DOCKET NO. 060188-0658	SERIAL NO. 10/671,502	
				APPLICANT Masashi HAMANAKA, et al.		
				FILING DATE September 29, 2003	GROUP 3723	
U.S. PATENT DOCUMENTS						
EXAMINER'S INITIALS	CITE NO.	Document Number Number-Kind Code ₂ (<i>if known</i>)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	
	US	6,107,203	08/22/2000	Vanell	Corresponds with CN 1216266 A	
	US	5,664,990	09/07/1997	Adams et al.	Corresponds with CN 1176864 A	
	US	5,755,614	05/26/1998	Adams et al.	Corresponds with CN 1176864 A	
	US	2002/0127860 A1	09/12/2002	Vanell	Corresponds with CN 1289628 A	
	US	6,592,708 B2	07/15/2003	Vanell	Corresponds with CN 1289628 A	
	US	6,423,638 B1	07/23/2002	Vanell	Corresponds with CN 1289628 A	
FOREIGN PATENT DOCUMENTS						
EXAMINER'S INITIALS	CITE NO.	Foreign Patent Document Country Code ₃ -Number &-Kind Codes (<i>if known</i>)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Figures Appear	Translation Yes No
		CN 1216266 A	05/12/1999	-	Corresponds with USP 6,107,203	X
		CN 1176864 A	03/25/1998	-	Corresponds with USP 5,755,614 & USP 5,664,990	X
		CN 1289628 A	04/04/2001	-	Corresponds with USP 2002/0127860 A1, USP 6,592,708 B2 and USP 6,423,638 B1	X
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)						
EXAMINER'S INITIALS	CITE NO.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.				
EXAMINER			DATE CONSIDERED			

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered.
Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.